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	Application No.	Applicant(s)	
Notice of Allowability	10/685,380	MAEKAWA, SHINJI	
	Examiner	Art Unit	
	David Goodwin	2818	
The MAILING DATE of this communication app All claims being allowable, PROSECUTION ON THE MERITS IS herewith (or previously mailed), a Notice of Allowance (PTOL-85 NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT F of the Office or upon petition by the applicant. See 37 CFR 1.31	S (OR REMAINS) CLOSED in b) or other appropriate comministing the comministing in the	n this application. If not included unication will be mailed in due cour	se. THIS
1. 🛛 This communication is responsive to <u>7/16/07</u> .			
2. 🛮 The allowed claim(s) is/are <u>1-73</u> .			
<ol> <li>Acknowledgment is made of a claim for foreign priority t</li> <li>a)    ☐ All b) ☐ Some* c) ☐ None of the:</li> </ol>		or (f).	
1. 🖾 Certified copies of the priority documents hav	· ·		
2. Certified copies of the priority documents have	• •		
3. Copies of the certified copies of the priority de	ocuments have been receive	d in this national stage application	from the
International Bureau (PCT Rule 17.2(a)).  * Certified copies not received:			
Applicant has THREE MONTHS FROM THE "MAILING DATE noted below. Failure to timely comply will result in ABANDON THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.		e a reply complying with the require	ments
<ol> <li>A SUBSTITUTE OATH OR DECLARATION must be subr INFORMAL PATENT APPLICATION (PTO-152) which given</li> </ol>			CE OF
5. CORRECTED DRAWINGS ( as "replacement sheets") mu	ust be submitted.		
(a) including changes required by the Notice of Draftspel		w ( PTO-948) attached	
1) 🗌 hereto or 2) 🔲 to Paper No./Mail Date	<b>_</b> ·		
(b) including changes required by the attached Examined Paper No./Mail Date	r's Amendment / Comment o	r in the Office action of	
Identifying indicia such as the application number (see 37 CFR each sheet. Replacement sheet(s) should be labeled as such in			k) of
<ol> <li>DEPOSIT OF and/or INFORMATION about the dep- attached Examiner's comment regarding REQUIREMENT</li> </ol>			the
Attachment(s) 1. □ Notice of References Cited (PTO-892)	5. ☐ Notice of Ir	oformal Patent Application	
2. ☐ Notice of Draftperson's Patent Drawing Review (PTO-948)		ummary (PTO-413),	
3. ☐ Information Disclosure Statements (PTO/SB/08),	Paper No.	/Mail Date Amendment/Comment	
Paper No./Mail Date  4. Examiner's Comment Regarding Requirement for Deposit	8. 🛛 Examiner's	Statement of Reasons for Allowan	ice
of Biological Material	9. 🗌 Other		
·	SUF	STEVEN LOKE PERVISORY PATENT EXAMINE	ER
		It Ist	

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## **DETAILED ACTION**

## Election/Restrictions

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1. Claims 1- are directed to an allowable product. Pursuant to the procedures set forth in MPEP § 821.04(B), claims 10-36, directed to the process of making or using an allowable product, previously withdrawn from consideration as a result of a restriction requirement, are hereby rejoined and fully examined for patentability under 37 CFR 1.104.

Because all claims previously withdrawn from consideration under 37 CFR 1.142 have been rejoined, the restriction requirement as set forth in the Office action mailed on 4/6/06 is hereby withdrawn. In view of the withdrawal of the restriction requirement as to the rejoined inventions, applicant(s) are advised that if any claim presented in a continuation or divisional application is anticipated by, or includes all the limitations of, a claim that is allowable in the present application, such claim may be subject to provisional statutory and/or nonstatutory double patenting rejections over the claims of the instant application. Once the restriction requirement is withdrawn, the provisions of 35 U.S.C. 121 are no longer applicable. See *In re Ziegler*, 443 F.2d 1211, 1215, 170 USPQ 129, 131-32 (CCPA 1971). See also MPEP § 804.01.

## Allowable Subject Matter

- 2. Claims 1-73 are allowed.
- 3. A method of manufacturing a semiconductor device, comprising the steps of: forming a crystalline semiconductor film containing a metal element over a transparent substrate; irradiating a first region of the crystalline semiconductor film with a first laser

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beam in a direction from the crystalline semiconductor film to the substrate after forming the crystalline semiconductor film; and irradiating the first region of the crystalline semiconductor film with a second laser beam through the substrate in a direction from the substrate to the crystalline semiconductor film while irradiating a second region of the crystalline semiconductor film with the first laser beam wherein the first region and the second region do not overlap each other.

## Conclusion

Any inquiry concerning this communication or earlier communications from the examiner should be directed to David Goodwin whose telephone number is (571)272-8451. The examiner can normally be reached on Monday through Friday, 9:00am through 5:00pm.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Steven Loke can be reached on (571)272-1657. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

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Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free). If you would like assistance from a USPTO Customer Service Representative or access to the automated information system, call 800-786-9199 (IN USA OR CANADA) or 571-272-1000.

DJG

STEVEN LOKE SUPERVISORY PATENT EXAMINER